

## *Corrigendum to*

# “Fabrication of Probe Beam by Using Joule Heating and Fusing” published in J. Sensor Sci. & Tech. Vol. 22, No. 1, pp. 89-94, 2013.

Pyo-Hwan Hong<sup>1</sup>, Dae-Young Kong<sup>1</sup>, Dong-In Lee<sup>1,2</sup>, Bonghwan Kim<sup>3</sup>, Chan-Seob Cho<sup>4,+</sup>, and Jong-Hyun Lee<sup>1</sup>

In the version of this article initially published, Bonghwan Kim was absent. The error has been corrected.

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<sup>1</sup>경북대학교 전자전기컴퓨터학부(School of Electronics Engineering, Kyungpook National University)

702-701, Kyungpook National University, Sangyeok 3-dong, Buk-gu, Daegu, Korea

<sup>2</sup>엠투랩(M2lab)

702-010, M2lab, Sangyeok-dong, Buk-gu, Daegu, Korea

<sup>3</sup>대구가톨릭대학교 전자공학부(Department of Electronics Engineering, Catholic University Daegu)

712-702, Daegu Catholic University, Geumnak-ri, Hayang-eup, Gyeongsan-si, Gyeongbuk, Korea

<sup>4</sup>경북대학교 산업전자전기공학부(School of Electrical Engineering, Kyungpook National University)

742-711, Kyungpook National Univ. Sangju Campus, Gajang-dong, Sangju-si, Gyeongbuk, Korea

<sup>+</sup>Corresponding author: choes@knu.ac.kr

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